

XEI SCIENTIFIC, INC.

Evactron® RF Plasma Cleaning Systems for Electron Microscopes

CE Declaration of Conformity

Manufacturer: XEI Scientific, Inc.
1755 East Bayshore Rd. Ste. 17, Redwood City, CA 94063
(650) 369-0133, FAX (650) 363-1659
www.Evactron.com, Rvane@Evactron.com

Model: Evactron® Models C, 10, 25, 40, 45 De-Contaminator

Type of Equipment: RF Plasma Cleaning System for vacuum systems

Application of Council Directives(s): 73/23/EEC as last amended by EC Directive 93/68/EEC (Low Voltage Directive) 98/37/EC (Machinery Directive)
2004/108/EC EMC directive

Testing Provider Notified Body, and Certification body: TUV Rheinland of North America, San Francisco Office
1279 Quarry Lane
Pleasanton, CA 94586

Tests: Confirmation of conformity to the Low Voltage and Machinery Directive:
IEC 61010-1:2001 & Annex I of 98/37/EC (Machinery Directive)
TUV: file number 30372945.004 , .005 and .014

Certificate of Conformity to Electromagnetic Compatibility
EC Directive 89/336/EC as amended by EC Directive 93/68/EEC as last amended by 2004/108/EC
Tested acc. to: EN 61326: 1997+A1+A2
TUV Report Nos. 30372945.005, 30372945.006, & 30372945.011
Registration No. AE 72032483 0001

I, the Undersigned, hereby declare that the equipment above conforms to the above Directives and Standards, when installed in accordance with the manufacturer's specifications.

Place of Issue: Redwood City, CA

Ronald Vane

Date of Issue: November 5, 2007 updated March 15, 2010

Ronald Vane - President